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PATENT

94326

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application

Applicant: Takashi YOKOYAMA et al.

Serial No.: Unassigned

Filed: May 11, 2005

For: SILICON WAFER, ITS MANUFACTURING METHOD,
AND ITS MANUFACTURING APPARATUS

PRELIMINARY AMENDMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Preliminary to the examination of the above application, please amend as follows: